VALQUA Semiconductor Industry Products

LABE ARMOR™

High Performance Modified Fluoro-silicone

Product & Benefits

LABE ARMOR[™] is Valqua's enhanced fluoro-silicone O-Ring. Its low adhesion to quartz and plasma resistance makes it suitable for static locations in ashing and etching equipment.

Featured Benefits

- Valqua's Fluorosilicone Grade Sealing Material with O₂ Plasma Resistance
- Applicable to Low Temperature Locations as low as -65℃

Applications

- Seals for Plasma Equipment
- Plasma Ashing Equipment
- Chillers and Other Cooling Equipment

Contact Us

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Typical Properties

Color	Blue
Hardness (Shore A)	75
Tensile Strength (MPa)	8.8
Elongation (%)	220
Modulus 100% Elongation (MPa)	4.3
Maximum Temperature (°C)	200

Values above are actual measurements, not standards



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Additional information

LABE ARMOR[™]

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Actual Equipment Evaluation Example

Performance Properties *

Magnification	OŤ	Etched	Area
0			

Equipment: Asher	Plasma Power: 1300W
Process Temp: 250 °C	Time: 3 months
Vacuum: 2.8 Torr	Gas : 02, N2

Fluoro-silicone Rubber





Material	Initial Hardness (as measured)	Etched Area Hardness
Fluoro-silicone Rubber	74	99 (+25)
LABE ARMOR™	78	89 (+11)